

L Number	Hits	Search Text	DB	Time stamp
-	0	(h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)).CCLS.	JPO; DEFWENT	2002/07/25 13:43
-	1126	h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)	USPAT; US-PGPUB	2002/06/17 16:43
-	96	(h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)) and (uv or (ultra adj violet))	USPAT; US-PGPUB	2002/06/17 16:33
-	117	(h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)) and static and gas	USPAT; US-PGPUB	2002/06/17 16:33
-	7	h011021/\$.ipc. and (work or susceptor) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)	JPO; DEFWENT	2002/06/17 16:51
-	7	h011021/\$.ipc. and (work or susceptor or pedestal) and conduct\$4 and insulat\$4 and ((silicon adj carbide) or titanium)	JPO; DEFWENT	2002/06/17 16:52
-	543	h011021/\$.ipc. and (work or susceptor or pedestal) and conduct\$4 and insulat\$4	JPO; DEFWENT	2002/06/17 16:53
-	120	h011021/\$.ipc. and (work or susceptor or pedestal) and conduct\$4 and insulat\$4 and (silicon or titanium)	JPO; DEFWENT	2002/06/17 17:02
-	18	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and conduct\$4 and insulat\$4 and (silicon or titanium)	JPO; DEFWENT	2002/06/17 17:39
-	528	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) and conduct\$4	JPO; DEFWENT	2002/06/17 17:42
-	227	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film)) and gas\$2	JPO; DEFWENT	2002/06/17 17:44
-	227	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2	JPO; DEFWENT	2002/06/23 16:11
-	1	(h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) and (conduct\$4 or (conductive adj film))and gas\$2) and static	JPO; DEFWENT	2002/07/24 13:34
-	93	c23c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2	JPO; DEFWENT	2002/06/17 17:45
-	0	c23c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3	JPO; DEFWENT	2002/06/17 18:41
-	0	(c23c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2) and ground\$3 and static	JPO; DEFWENT	2002/06/17 17:47
-	9	(c23c016/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2) and ground\$3	JPO; DEFWENT	2002/06/17 18:21
-	64	156/345.5.ccls.	USPAT; US-PGPUB	2002/06/17 18:10
-	19	156/345.5.ccls. and conduct\$3 and insulat\$3	USPAT; US-PGPUB	2002/06/17 18:14
-	34	118/\$.ccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2002/07/24 14:01

-	287	118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same (silicon adj carbide)or SiC or titanium)and gas\$2	USPAT; US-PGPUB	2002/06/18 15:41
-	1	5904778.pn.	USPAT; US-PGPUB	2002/06/18 10:12
-	218	118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same (silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PGPUB	2002/07/23 16:07
-	218	(118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same (silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) and (conduct\$4 or gas or ground\$3)	USPAT; US-PGPUB	2002/06/18 14:13
-	15	((156/345.\$2).cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same (silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PGPUB	2002/06/18 14:03
-	11	((156/345.\$2).cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same (silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) not ((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) and (conduct\$4 or gas or ground\$3))	USPAT; US-PGPUB	2002/06/18 14:09
-	1440	(tokyo adj electron).as.	USPAT; US-PGPUB	2002/06/18 14:10
-	20	((tokyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2	USPAT; US-PGPUB	2002/06/18 14:24
-	20	((tokyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2) and (conduct\$4 or gas or ground\$3)	USPAT; US-PGPUB	2002/06/18 14:25
-	310	((tokyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))	USPAT; US-PGPUB	2002/06/18 14:25
-	291	((tokyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))) and (conduct\$4 or gas or ground\$3)	USPAT; US-PGPUB	2002/06/18 14:48
-	20	((tokyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))) and conduct\$4 and ground\$3 and static	USPAT; US-PGPUB	2002/07/24 10:40
-	20	((tokyo adj electron).as.) and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder))) and conduct\$4 and ground\$3 and static) not electrostatic	USPAT; US-PGPUB	2002/06/18 14:54
-	0	h011001/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and static and ground\$2	JPO; DEFWENT	2002/06/18 15:23
-	42	h011001/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and ground\$2	JPO; DEFWENT	2002/06/18 15:25

-	6	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder)) or (substrate adj holder)) and conduct\$3 and ground\$2 and (static or charge)	JPO; DEFWENT	2002/06/18 15:37
-	1	6:947:2.pn.	JPO; DEFWENT	2002/06/18 15:38
-	1	6:947:2.pn.	USPAT; US-PGPUB	2002/06/18 15:38
-	164	118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and (static or charge) and ground\$3	USPAT; US-PGPUB	2002/06/18 15:45
-	34	118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2002/06/18 15:49
-	130	((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and (static or charge) and ground\$3) not ((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3)	USPAT; US-PGPUB	2002/06/18 16:32
-	109	((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and (static or charge) and ground\$3) not ((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3)) and film	USPAT; US-PGPUB	2002/06/18 16:33
-	45	((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and (static or charge) and ground\$3) not ((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3)) and conductiv\$2 with film	USPAT; US-PGPUB	2002/06/18 16:35
-	45	((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and (static or charge) and ground\$3) not ((118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder)) and (conduct\$4 or (conductive adj film))and gas\$2 and static and ground\$3)) and (conductiv\$2 with film)	USPAT; US-PGPUB	2002/06/18 16:36
-	6	h011021/\$.ipc. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) and conduct\$3 and (static or charge) and ground\$2	JPO; DEFWENT	2002/06/18 17:25
-	32	118/\$.cccls. and ((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2 and (charge or static)	USPAT; US-PGPUB	2002/06/18 17:56
-	104	((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide)or SiC or (titanium adj oxide))and gas\$2 and (charge or static)and (vacuum or exhaust)and conduct\$3	USPAT; US-PGPUB	2002/06/18 18:05

-	57	((work adj table) or susceptor or pedestal or (work adj holder) or (substrate adj holder)) same ((silicon adj carbide) or SiC or (titanium adj oxide)) and gas\$2 and (charge or static) and (vacuum or exhaust) and conduct\$3 and ground\$2	USPAT; US-PGPUB	2002/06/18 18:06
-	1	6106630.pn.	USPAT; US-PGPUB	2001/07/23 13:12
-	1	5878450.pn.	USPAT; US-PGPUB	2001/07/23 16:08
-	0	h011021/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer) and dechuck\$4	JPO; DEFWENT	2001/07/23 16:27
-	0	(h011021/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and dechuck\$4	JPO; DEFWENT	2002/07/23 16:29
-	302	h011021/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)	JPO; DEFWENT	2001/07/23 16:30
-	285	(h011021/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522	JPO; DEFWENT	2001/07/24 10:43
-	285	(h011021/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522	JPO; DEFWENT	2002/07/24 10:29
-	11	(c033016/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522) not ((h011021/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522)	JPO; DEFWENT	2002/07/24 10:30
-	37	((tokyo adj electron).as.) and (susceptor or pedestal or work or substrate) and conduct\$4 and ground\$3 and static	USPAT; US-PGPUB	2001/07/24 10:52
-	209	118/\$.ccls. and (work or susceptor or pedestal or substrate) and conduct\$4 and static and ground\$3	USPAT; US-PGPUB	2001/07/24 11:54
-	2	"10070151"	JPO; DEFWENT	2001/07/24 11:46
-	2	"10110888"	JPO; DEFWENT	2001/07/24 11:49
-	41	(c033016/\$.ipc. and (work or susceptor or pedestal) with conduct\$4 with (film or layer)) and @ad<20000522	JPO; DEFWENT	2001/07/24 11:54
-	2	"01040712"	JPO; DEFWENT	2001/07/24 12:55
-	168	156/345.51.ccls.	USPAT; US-PGPUB	2002/07/24 13:14
-	151	156/345.51.ccls. and @ad<20000522	USPAT; US-PGPUB	2001/07/24 13:14
-	100	(156/345.51.ccls. and @ad<20000522) and conduct\$4	USPAT; US-PGPUB	2001/07/24 13:20
-	51	(156/345.51.ccls. and @ad<20000522) and conduct\$4 and ground\$3	USPAT; US-PGPUB	2002/07/24 13:20
-	43	(361/010-224 ccls.) and (susceptor or pedestal or work or substrate) and conduct\$4 and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2001/07/24 13:01
-	323	(work or susceptor or pedestal or (substrate adj holder)) with (conduct\$4 or (conductive adj (film or layer))) and gas\$2 and static and ground\$3	USPAT; US-PGPUB	2001/07/24 14:14
-	299	((work or susceptor or pedestal or (substrate adj holder)) with (conduct\$4 or (conductive adj (film or layer))) and gas\$2 and static and ground\$3) and @ad<20000522	USPAT; US-PGPUB	2001/07/24 14:15
-	1	4691230.pn.	USPAT; US-PGPUB	2001/07/25 12:11
-	1	4873549.pn.	USPAT; US-PGPUB	2002/07/25 12:11